Conduction Cooled Laser Bar Stack

*C-Stack* λ780-830nm

**Features:**
- Improved cooling efficiency
- No “smile” effect
- Bars on demand
- Central wavelength on demand

**Suitable for:**
- Hair Removal
- Surgical Cardiology
- Ophthalmology
- Interstitial Laser induced Thermotherapy (Cancer)
- Odontology
- Material processing
- Printing

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C-STACK / 780-830nm

Product specification are subject to change without notice. For complete details, please contact your local MONOCROM sales representative.

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### Laser Parameters

<table>
<thead>
<tr>
<th>Parameter</th>
<th>Specification</th>
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</thead>
<tbody>
<tr>
<td>Type</td>
<td>conduction cooled stack</td>
</tr>
<tr>
<td>Wavelength(^1) [nm]</td>
<td>780 - 830</td>
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<tr>
<td>Wavelength tolerance [nm]</td>
<td>±20</td>
</tr>
<tr>
<td>Spectral width [nm]</td>
<td>3</td>
</tr>
<tr>
<td>Wavelength shift [nm/K]</td>
<td>0.27</td>
</tr>
<tr>
<td>Output power(^2,8) [W]</td>
<td>CW - up to 100 / QCW - up to 500</td>
</tr>
<tr>
<td>Operating current [A]</td>
<td>CW &lt; 120 / QCW &lt; 480</td>
</tr>
<tr>
<td>Efficiency coefficient [W/A]</td>
<td>1.2</td>
</tr>
<tr>
<td>Voltage @ connectors(^6) [V]</td>
<td>2 - 30</td>
</tr>
<tr>
<td>Bar to bar pitch [mm]</td>
<td>down to 1.5</td>
</tr>
<tr>
<td>Optics (optional)</td>
<td>FAC / SAC / BT</td>
</tr>
<tr>
<td>Bars per stack(^5)</td>
<td>1 - 15</td>
</tr>
<tr>
<td>Smile [µm]</td>
<td>&lt; 0.3</td>
</tr>
</tbody>
</table>

1. Other wavelengths on request.
2. Expected output power. Can varies based on current and temperature.
3. Specification are subjected to chips availability.
4. Voltage from the power supply must be higher, as due to high current there will be a voltage drop in the cables.
5. Pitch dependent

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### No Mechanical Stress

Our patented solder-free technology is used in our diode bars stacks. Thanks to it clamped bars expand and contract freely during the thermal cycles of the pulsed regime avoiding mechanical stress.

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